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# U.S. UTILITY Patent Application

ISSUE DATE

APPL NUM 10004168	FILING DATE 10/30/2001	CLASS 438	SUBCLASS 4	GAU 2812	EXAMINER 2825
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\*\*CONTINUING DATA VERIFIED:

\*\* FOREIGN APPLICATIONS VERIFIED:  
JAPAN 2000-334915 10/30/2000

PG-PUB DO NOT PUBLISH ☐

RESCIND ☐

Foreign priority claimed ☐ yes ☐ no  
35 USC 119 conditions met ☐ yes ☐ no

ATTORNEY DOCKET NO

Verified and Acknowledged Examiners's initials

16869P-037300US

TITLE : Inspection system and semiconductor device manufacturing method

U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		Primary Examiner	DRAWING	
Amount Due	Date Paid		Sheets Drwg.	Figs. Drwg.
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	Application Examiner	
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